

# Optics Letters

## Polarization-independent photonic Bragg grating filter with cladding asymmetry

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**A photonic Bragg grating is a fundamental building block that reflects the direction of wave propagation through spatial phase modulation and can be implemented using sidewall corrugation. However, due to the asymmetric aspect ratio of a waveguide cross section, typical Bragg gratings exhibit a strong polarization sensitivity. Here, we show that photonic Bragg gratings with cladding asymmetry can enable polarization-independent notch filters by rotating input polarizations. Such Bragg gratings strongly couple transverse electric (TE) and transverse magnetic (TM) modes propagating in opposite directions, filtering the input signal and reflecting the rotated mode. We analyzed this polarization-rotating Bragg grating using the coupled-mode theory and experimentally demonstrated it on a silicon-on-insulator platform. Our device concept is simple to implement and compatible with other platforms, readily available as polarization transparent Bragg components.** © 2023 Optica Publishing Group

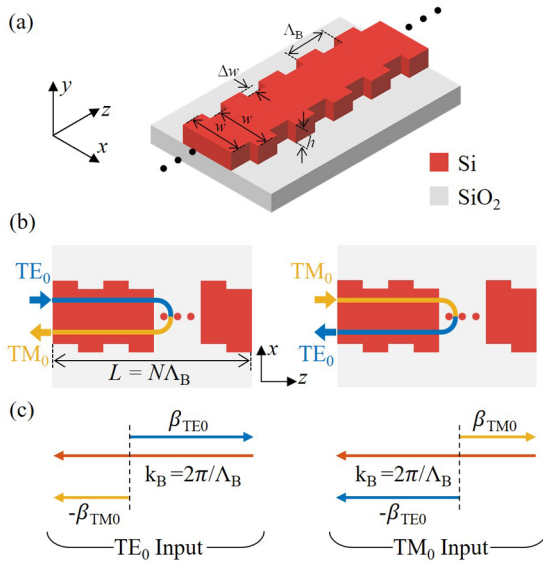
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A Bragg grating is a distributed reflector consisting of a periodic structure such that the spatial phase modulation reflects the input waves [1–3]. At the Bragg condition, multiple reflections from each periodic boundary interfere constructively, forming a strong and narrow reflection band centered at a wavelength, namely the Bragg wavelength. At wavelengths other than the Bragg condition, the reflected lights interfere destructively due to phase mismatching, resulting in the input light being transmitted through the gratings. As a result, Bragg gratings function as notch filters. In integrated photonics, Bragg gratings are implemented using either sidewall corrugation in the waveguide core (i.e., by changing the waveguide width or height) [1–3] or periodic grating patterns in the cladding [4,5]. Bragg gratings have been utilized for a wide range of advanced applications, including spectral filtering [4], pulse shaping [6], dispersion compensation [7], wavelength division multiplexing [8], and optical signal processing [9]. However, photonic Bragg grating is intrinsically sensitive to polarizations due to their different modal indices, matching the Bragg condition at different

wavelengths. This polarization dependency of a Bragg grating limits the system to being operated only at a single polarization. The size of a Bragg grating is typically large (as its reflectivity increases per number of periods); thus, having separate Bragg gratings for transverse electric (TE) and transverse magnetic (TM) modes increases the system size and complexity drastically, which is detrimental to the whole system.

One approach to making the Bragg grating insensitive to input polarization is matching the effective indices of TE and TM modes [10–12]. Various approaches can be considered to achieve this, such as symmetric waveguide height and width [10], cross-slot waveguide [11], and index engineering via sub-wavelength gratings [12]. However, such an approach would still cause different reflection coefficients for each polarization, resulting in different extinction ratios and bandwidths while matching the Bragg wavelength. Alternatively, polarization-rotating Bragg gratings can be established, which naturally achieve polarization-insensitive filtering [13–17]. By making the grating cross sections asymmetric, one can strongly couple TE and TM modes; then, both modes can be used to satisfy the Bragg condition regardless of the input polarization. Breaking the vertical symmetry is the key to implementing this, but most approaches used double etching or angled sidewall, adding more complexity to the process with low accuracy.

In this paper, we show that single-etched photonic Bragg gratings with cladding asymmetry can effectively achieve polarization-independent Bragg filtering. We use air cladding to introduce the cladding asymmetry on a single-etched monolithic device, efficiently coupling TE and TM modes for polarization rotation. The Bragg condition is satisfied at the average of TE and TM modes, filtering the input polarization mode and reflecting the rotated mode. We use coupled mode theory to design our Bragg gratings and to quantify the coupling strength between TE and TM modes. We experimentally demonstrate this on a single-etched 220 nm thick silicon-on-insulator (SOI) platform, confirming its polarization-independent Bragg filtering. Figure 1(a) shows the schematic of the proposed polarization-independent photonic Bragg grating. Red and gray represent Si and SiO<sub>2</sub>, respectively. The Bragg gratings are designed by alternating a simple rectangular strip waveguide (height  $h = 220$  nm



**Fig. 1.** (a) Schematic view of the proposed polarization-independent Bragg grating with cladding asymmetry: Si (red) and SiO<sub>2</sub> (gray). (b) Top view of the gratings, illustrating the polarization rotation and reflection at the Bragg condition (left, TE<sub>0</sub> input; right, TM<sub>0</sub> input). The waveguide height and width are  $h = 220$  nm and  $w = 450$  nm, respectively, with the corrugation depth  $\Delta w = 50$  nm. The Bragg periodicity and the number of periods are  $\Lambda_B = 390\text{--}420$  nm and  $N = 100\text{--}500$ , respectively. (c) Phase diagrams of the polarization rotating Bragg reflection: left, TE<sub>0</sub> input; right, TM<sub>0</sub> input.

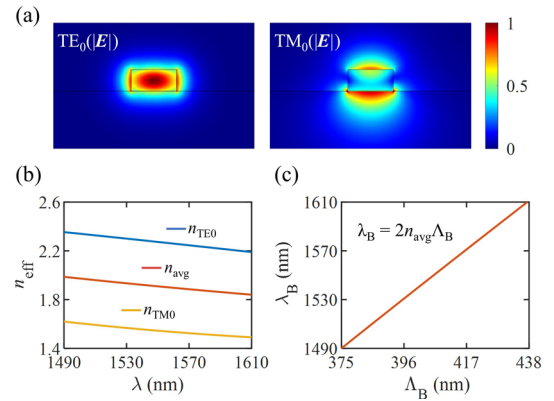
and width  $w = 450$  nm) with a corrugation offset  $\Delta w = 50$  nm and the Bragg periodicity  $\Lambda_B = 390\text{--}420$  nm. Air cladding is presented, introducing vertical cladding asymmetry. The number of periods ranges  $N = 100\text{--}500$ , and the total device length is  $L = N \cdot \Lambda_B$ . Figure 1(b) shows the top view of the Bragg grating, illustrating the polarization rotation and reflection with the fundamental TE (TE<sub>0</sub>, left) and TM (TM<sub>0</sub>, right) inputs at the Bragg condition. Figure 1(c) shows the corresponding phase diagrams, satisfying the Bragg conditions with polarization rotations: TE<sub>0</sub> (left) and TM<sub>0</sub> (right) inputs. Notice that, regardless of the input polarization, the Bragg condition satisfies

$$\Delta\beta = \beta_{TE0} - (-\beta_{TM0}) - \frac{2\pi}{\Lambda_B} = 0, \quad (1)$$

where  $\beta_{TE0}$  and  $\beta_{TM0}$  represent the propagation constants for the TE<sub>0</sub> and TM<sub>0</sub> modes, respectively. The magnitude of the propagation constant  $\beta_{TE0}$  is typically larger than  $\beta_{TM0}$ , since TE<sub>0</sub> has a larger effective index with a higher field confinement. This is also depicted in Fig. 1(c). By inserting  $\beta_{TE0} = (2\pi n_{TE0})/\lambda_B$  and  $\beta_{TM0} = (2\pi n_{TM0})/\lambda_B$  into Eq. (1), we can obtain the Bragg wavelength  $\lambda_B$  at which the reflection is maximum,

$$\lambda_B = (n_{TE0} + n_{TM0})\Lambda_B = 2n_{avg}\Lambda_B, \quad (2)$$

where  $n_{avg} = (n_{TE0} + n_{TM0})/2$  is the average effective index between the TE<sub>0</sub> and TM<sub>0</sub>. Notice that all the effective indices  $n_{TE0}(\lambda_B)$ ,  $n_{TM0}(\lambda_B)$ , and  $n_{avg}(\lambda_B)$  are as a function of wavelength; thus, Eq. (2) should be solved numerically. To find out the Bragg periodicity  $\Lambda_B$  associated with the Bragg wavelength  $\lambda_B$  near the telecommunication band, we simulated the modal properties of TE<sub>0</sub> and TM<sub>0</sub>. Figure 2(a) shows the simulated mode profiles  $|E|$  of TE<sub>0</sub> (left) and TM<sub>0</sub> (right) modes, and Fig. 2(b) shows



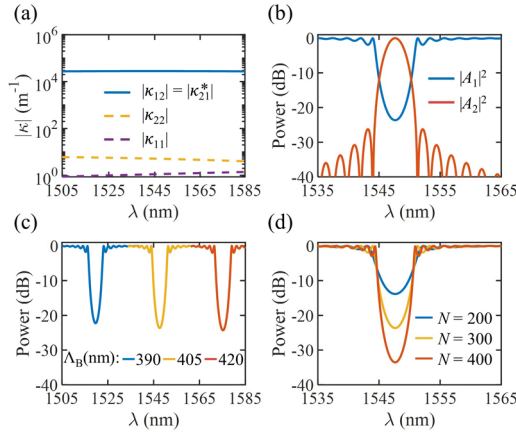
**Fig. 2.** (a) Normalized electric field profiles ( $|E|$ ) of the strip waveguide: TE<sub>0</sub> (left) and TM<sub>0</sub> (right) modes. (b) Simulated effective refractive indices of the TE<sub>0</sub> ( $n_{TE0}$ , blue) and TM<sub>0</sub> ( $n_{TM0}$ , yellow) modes. The orange line represents the average  $n_{avg}$  between  $n_{TE0}$  and  $n_{TM0}$ . (c) Theoretical estimate of the Bragg wavelength  $\lambda_B$  as a function of the Bragg period  $\Lambda_B$ , using Eq. (2).

their effective refractive indices as a function of wavelength for TE<sub>0</sub> (solid blue line) and TM<sub>0</sub> (solid yellow line). The average effective index  $n_{avg}$  is also plotted with a solid orange line. We numerically solved Eq. (2) using the graphical method, and Fig. 2(c) presents the theoretically estimated Bragg wavelength as a function of the Bragg period. Based on this, we chose the Bragg periodicity in the range of  $\Lambda_B = 390\text{--}420$  nm, having  $\lambda_B$  near 1550 nm. Note that, since our Bragg grating has identical cross sections in each layer, this estimate is independent of the corrugation offset  $\Delta w$  and gives a good prediction for the Bragg wavelength.

To confirm the Bragg wavelength estimations and assess its polarization-independency, we analyzed our Bragg gratings using the coupled-mode theory (CMT). First, we ran the modal simulations and calculated the coupling coefficients  $\kappa_x$ ,  $\kappa_y$ , and  $\kappa_z$ , given by [1]

$$\kappa_i = \frac{\omega\epsilon_0}{4} b_m \iint E_{1i}^*(x, y) \cdot \Delta\epsilon_i(x, y) E_{2i}(x, y) dx dy, \quad (3)$$

where the subscript  $i = x, y$ , and  $z$ . The  $b_m$  is the Fourier expansion coefficient of the periodic waveguide grating. The  $\Delta\epsilon_i$  denotes the dielectric perturbation due to the sidewall corrugation  $\Delta w$ . The  $E_{1i}(x, y)$  and  $E_{2i}(x, y)$  are normalized electric fields of the two interacting modes, here the subscripts 1 and 2 represent TE<sub>0</sub> and TM<sub>0</sub> modes, respectively. The overall coupling coefficient can be represented by adding the coefficients from each field component, i.e.,  $|\kappa| = |\kappa_x + \kappa_y + \kappa_z|$ . Figure 3(a) shows the magnitude of the calculated coupling coefficients:  $|\kappa_{11}|$  (purple dashed) and  $|\kappa_{22}|$  (yellow dashed) represent the TE<sub>0</sub> to TE<sub>0</sub> and TM<sub>0</sub> to TM<sub>0</sub> couplings, respectively, and  $|\kappa_{12}| = |\kappa_{21}|$  (blue solid) represents the coupling between TE<sub>0</sub> and TM<sub>0</sub> modes. Notice the high coupling coefficient between TE<sub>0</sub> and TM<sub>0</sub> modes (i.e.,  $|\kappa_{12}| = |\kappa_{21}|$ ) compared with others. This clearly indicates the strong coupling between TE<sub>0</sub> and TM<sub>0</sub> modes, which means the rotation of polarizations through this Bragg grating. The  $\kappa_{11}$  and  $\kappa_{22}$  are very low ( $<10\text{ m}^{-1}$ ), avoiding the side Bragg responses from TE<sub>0</sub> to TE<sub>0</sub> and TM<sub>0</sub> to TM<sub>0</sub> couplings (see Supplement 1).

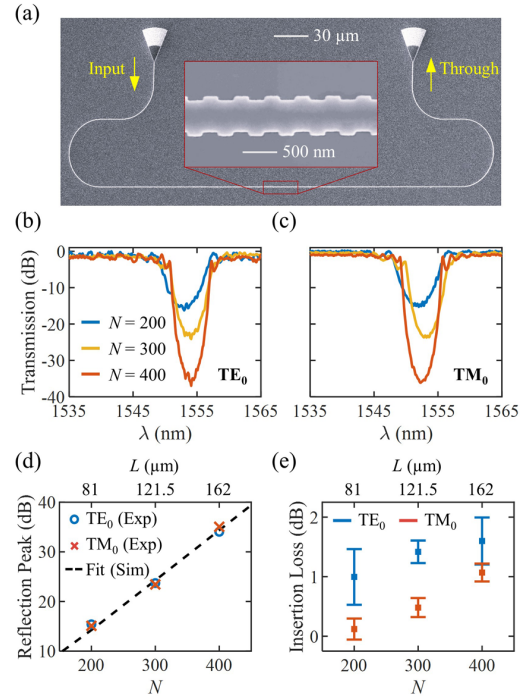


**Fig. 3.** (a) Calculated coupling coefficients using Eq. (3). The solid blue line represents the coupling coefficient between TE<sub>0</sub> and TM<sub>0</sub> modes ( $|\kappa_{12}| = |\kappa_{21}^*|$ ). The dashed yellow and purple lines are the coupling coefficients of TM<sub>0</sub> to TM<sub>0</sub> ( $|\kappa_{22}|$ ) and TE<sub>0</sub> to TE<sub>0</sub> ( $|\kappa_{11}|$ ) modes, respectively. (b) Calculated transmission  $|A_1|^2$  and reflection  $|A_2|^2$  using Eq. (4) ( $\Lambda_B = 405$  nm and  $N = 300$ ). Similar transmission spectra while varying (c) the periodicity  $\Lambda_B = 390$  (blue), 405 (yellow), and 420 (orange) nm (fixing the  $N = 300$ ) and (d) the number of periods  $N = 200$  (blue), 300 (yellow), and 400 (orange) (fixing the  $\Lambda_B = 405$  nm). Other parameters are the same as in Fig. 1.

Using these coupling coefficients, we numerically calculated the following coupled-mode equations [1]:

$$\begin{aligned} \frac{d}{dz}A_1 &= -i\kappa_{12}A_2(z)e^{i\Delta\beta z}, \\ \frac{d}{dz}A_2 &= i\kappa_{21}A_1(z)e^{-i\Delta\beta z}, \end{aligned} \quad (4)$$

where,  $A_1$  and  $A_2$  are the amplitudes of the forward (input) and backward (reflected) propagating modes, respectively. Note that the phase difference  $\Delta\beta$  is from Eq. (1) and zero at the Bragg wavelength, achieving the peak reflection. Figure 3(b) shows the calculated transmission  $|A_1|^2$  (blue) and reflection  $|A_2|^2$  (orange) spectra using Eq. (4) when  $\Lambda_B = 405$  nm and  $N = 300$ . Other parameters are the same as described in Fig. 1, unless otherwise addressed. Since the Bragg wavelength appears at the average of TE<sub>0</sub> and TM<sub>0</sub> and the coupling coefficients are the same, exciting TE<sub>0</sub> or TM<sub>0</sub> would not differ in spectral response, i.e., polarization independent. Furthermore, as expected, the peak reflection appears at  $\approx 1548$  nm, which matches with Fig. 2(c). Changing the grating period  $\pm 15$  nm shifts the Bragg wavelength approximately to  $\pm 28$  nm, as shown in Fig. 3(c). The total number of periods  $N$  would not affect the Bragg wavelength's spectral location, but it defines the degree of reflection, i.e., peak reflection and spectral sharpness. The transmission spectra varying  $N = 200, 300$ , and 400 are shown in Fig. 3(d), increasing the degree of reflection as  $N$  increases. We then fabricated our devices on an SOI wafer comprising a 220 nm thick Si layer and a 2  $\mu$ m thick SiO<sub>2</sub> layer. Electron beam lithography was used to define the device patterns. We fabricated two sets of devices with TE and TM grating couplers to ensure polarization status during the characterization. Figure 4(a) shows the scanning electron microscope images of the fabricated device set with the zoomed-in image showing the Bragg gratings.

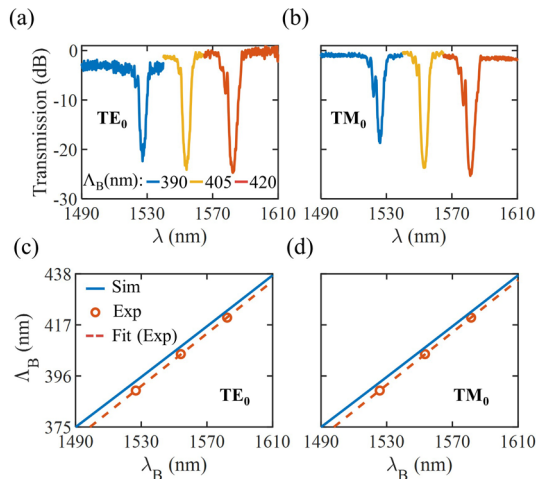


**Fig. 4.** (a) Scanning electron microscope image of the fabricated device (zoomed-in image: Bragg grating). Experimentally characterized transmission spectra for (b) TE<sub>0</sub> and (c) TM<sub>0</sub> inputs:  $N = 200$  (blue); 300 (yellow); and 400 (orange). The Bragg periodicity is fixed at  $\Lambda_B = 405$  nm. (d) Extracted peak reflections for different  $N$  and  $L$ : TE<sub>0</sub> (blue circles) and TM<sub>0</sub> (orange crosses) inputs. Black dashed line is the numerical result. (e) Insertion losses for different  $N$  and  $L$ : TE<sub>0</sub> (blue) and TM<sub>0</sub> (orange).

We characterized the devices using a custom-built grating coupler setup with a tunable laser source and an optical power meter. A polarization controller was connected after the laser source, controlling the input polarization. The calibration devices without Bragg structures were also fabricated and used to normalize the spectra. Figures 4(b) and 4(c) show the measured transmissions for TE<sub>0</sub> and TM<sub>0</sub> inputs, respectively, when  $\Lambda_B = 405$  nm. Different colors represent the different number of periods  $N = 200$  (blue), 300 (yellow), and 400 (orange). Notice that both TE<sub>0</sub> and TM<sub>0</sub> transmissions show almost identical spectra, having Bragg wavelengths differ only approximately  $\Delta\lambda_B \approx 0.1\text{--}0.7$  nm. We fabricated identical designs on two different chips, having TE<sub>0</sub> and TM<sub>0</sub> grating couplers. These different environments might cause a difference in  $\lambda_B$ , but we expect more identical spectra if we measure them within one chip. Since the number of period is less sensitive between chip-to-chip variations, the peak extinction ratios of the reflection are close, having  $<1.1$  dB difference between TE<sub>0</sub> and TM<sub>0</sub> data. These also match well with the simulated results in Fig. 3(d). The experimentally measured reflection peaks for TE<sub>0</sub> (blue circles) and TM<sub>0</sub> (orange crosses) are extracted in Fig. 4(d), providing excellent agreements with the simulated result (black dashed line). The insertion losses of the devices are also characterized in Fig. 4(e), by taking averages and standard deviations of off-Bragg wavelength transmissions. The uncertainty is mostly from grating coupler characterizing setup.

Figures 5(a) and 5(b) show the measured transmission spectra for TE<sub>0</sub> and TM<sub>0</sub> inputs, respectively, similar to Figs. 4(a) and





**Fig. 5.** Experimentally characterized transmission spectra for (a)  $TE_0$  and (b)  $TM_0$  inputs at different  $\Lambda_B = 390$  (blue), 405 (yellow), and 420 (orange) nm. The Bragg periodicity is fixed at  $N = 300$ . Extracted Bragg wavelength  $\lambda_B$  for each Bragg period  $\Lambda_B$  (orange circles); (c)  $TE_0$  and (d)  $TM_0$  inputs. The orange dashed lines are their fitting lines. The blue lines are numerical results from Fig. 2(c).

**Table 1. Summary of the Previously Reported Polarization-independent Photonic Bragg Gratings<sup>a</sup>**

Cladding asymmetry	FWHM (nm)	ER (dB)	$L$ ( $\mu\text{m}$ )
Angled sidewall [13]	1.5	18	1000
Double etch [15]	10	15	500
Double etch [17]	8	22	470
Double etch [16]	0.2	22	331
Double etch [14]	2.63	27	300
<b>Single etch (this work)</b>	<b><math>\approx 6</math></b>	<b><math>\approx 34</math></b>	<b>162</b>

<sup>a</sup>FWHM (full width at half maximum), ER (extinction ratio at peak reflection),  $L$  (device length).

4(b) but with different  $\Lambda_B$ , demonstrating Fig. 3(c). We also replot the numerically estimated  $\Lambda_B$  versus  $\lambda_B$  (solid blue line) and compare it with extracted  $\lambda_B$  (orange circles) in Figs. 5(c) and 5(d). The dashed orange line indicates the fitting line for the experimental data. The measured  $\lambda_B$  slightly redshifted  $\approx 6$  nm compared with the simulation results, probably due to fabrication imperfections and wafer non-uniformity. However, between  $TE_0$  and  $TM_0$ , the characterized  $\lambda_B$  agrees well within  $\approx 1.5$  nm wavelength, confirming its polarization independency.

Table 1 summarizes the previously reported polarization-independent Bragg filters, including this work. While most approaches utilized double-etching or angled sidewall for breaking the vertical symmetry, our asymmetric cladding approach can use single-etched monolithic PICs. We report polarization-independent Bragg filters with extinction ratios  $\approx 34$  dB and full width at half maximum (FWHM) bandwidth  $\approx 6$  nm for a 162  $\mu\text{m}$ -long device, which also can be engineered further by changing the  $\Delta w$  and  $N$ . Furthermore, while we used an air cladding to introduce the concept, the cladding asymmetry also can be implemented using other cladding materials such as low-index polymers. The same design methodology introduced here can be applied to designing polarization-independent Bragg filters, probably requiring more number of Bragg periods due to less index contrast.

In conclusion, we have proposed and experimentally demonstrated polarization-independent Bragg gratings by rotating input polarizations with cladding asymmetry. The cladding asymmetry is introduced on an SOI platform using air cladding, which can also be replaced by other low-index claddings or index-matching fluids. We designed our Bragg grating by alternating the same cross section strip waveguides with a fixed corrugation offset, which is simple to design and fabricate using a single-etching process. In support of the strong coupling between  $TE_0$  and  $TM_0$  modes, our device offers a compact length, achieving  $\approx 15$ –34 dB extinction ratios and  $\approx 6$ –8 nm FWHM for 81–162  $\mu\text{m}$ -long gratings. Demonstrated on a widely used SOI, our polarization-independent Bragg grating is readily available for advanced PICs, and the same concept can be easily applicable to other platforms and spectral regimes.

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**Disclosures.** The authors declare no conflicts of interest.

**Data availability.** Data underlying the results presented in this paper may be obtained from the authors upon reasonable request.

**Supplemental document.** See Supplement 1 for supporting content.

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